## Notice of References Cited Application/Control No. Applicant(s)/Patent Under Reexamination LITKE ET AL. Examiner Lance W. Sealey Art Unit Page 1 of 1

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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYYY format are publication dates. Classifications may be US or foreign.